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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

fe Application

Inventor(s):

Thomas F. Rust

Appln. No.:

10/684,883

Confirm. No.: 4852

10/14/2003

Filed: Title:

MOLECULAR MEMORY INTEGRATED

CIRCUIT UTILIZING NON-VIBRATING

CANTILEVERS

PATENT APPLICATION

Art Unit:

2655

Examiner:

not assigned

Customer No. 23910

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8

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(Attorney Signature)

Michael L. Robbins, Reg. No. 54,774 Signature Date: June 7, 2004

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.56

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

It is requested that the information identified in this statement be considered by the Examiner and made of record in the above-identified application. This statement is not intended to represent that a search has been made or that the information cited in the statement is, or is considered to be, material to patentability as defined in 37 C.F.R. §1.56. If this is a continuation, divisional or continuation-in-part application, it is understood that the Examiner will consider all information which was considered by the Office in a parent application. MPEP §609. Such information therefore is not listed herein unless it is desired that the information be printed on a patent issuing from the subject application.

Enclosed with this statement are the following:

<u> </u>	Form PTO-1449. The Examiner is requested to initial the form and return it to the undersigned in
	accordance with M.P.E.P. §609.

The present application is being/was filed after June 30, 2003. In accordance with the pre-official gazette waiver of 37 CFR 1.98 (a)(2)(i) posted at: pac/dapp/opla/preognotice/idswouscopies.htm, copies of cited U.S. patents and publications are not enclosed. However, copies of cited foreign patent documents and non-patent literature are enclosed in accordance with 37 CFR 1.98(a)(2), as still required, except for those items designated by an asterisk (*), which were previously submitted by the applicant in a parent application, from which benefit under 35 U.S.C. §120 is claimed, with an

Information Disclosure Statement submitted in the parent application which complies with the September 8, 2000 or subsequent revision of 37 C.F.R. §1.98(a-c), as allowed under 37 C.F.R. §1.98(d)(1).

- The present application was filed prior to June 30, 2003. A copy of each cited document as required by 37 C.F.R. §1.98 is enclosed, except for those items designated by an asterisk (*), which were previously submitted by the applicant in a parent application, from which benefit under 35 U.S.C. §120 is claimed, with an *Information Disclosure Statement* submitted in the parent application which complies with the September 8, 2000 or subsequent revision of 37 C.F.R. §1.98(a-c), as allowed under 37 C.F.R. §1.98(d)(1).
- If any of the cited/submitted documents is in a foreign language, a concise explanation of relevance is provided pursuant to 37 C.F.R. §1.98(a)(3)(i). For foreign language documents cited in a search report by a foreign patent office, the requirement for a concise explanation of relevance is satisfied by the submission herewith of an English language version of the search report. MPEP §609A(3). If a written English-language translation of a non-English language document, or portion thereof, is within the possession, custody or control of, or is readily available to any individual designated in §1.56(c), a copy of the translation accompanies this statement, 37 C.F.R. §1.98(a)(3)(ii), and satisfies the requirement for a concise explanation of relevance, MPEP §609A(3).
- __ PTA Statement under 37 C.F.R. §1.704(d). Each item of information contained in the Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart application and this communication was not received by any individual designated in §1.56(c) more than thirty days prior to the filing of the Information Disclosure Statement.

This statement should be considered because:

- ✓ 37 C.F.R. §1.97(b). This statement qualifies under 37 C.F.R. §1.97, subsection (b) because:
 - (1) It is being filed within three months of the filing date of an application other than a continued prosecution application under § 1.53(d);

-- OR --

- (2) It is being filed within 3 months of entry of a national stage;
 -- OR --
- (3) It is being filed before the mailing date of the first Office Action on the merits, -- OR --
- (4) It is being filed before the mailing date of the first Office Action after the filing of a Request for Continued Examination under 37 C.F.R. §1.114.
- ___ 37 C.F.R. §1.97(c). Although it may not qualify under subsection (b), this statement qualifies under 37 C.F.R. §1.97, subsection (c) because:
 - (1) It is being filed before the mailing date of a FINAL Office Action, a Notice of Allowance, or an action that otherwise closes prosecution in the subject application, whichever occurs first.
 - -- AND (check at least one of the following) --

			.(1)	It is accompanie	_	EMENT as s	set forth in 3	7 C.F.R. §1.97	7(e).
			(2)	It is accompanie		fee set fortl	h in 37 C.F.I	R. §1.17(p).	
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		(1)	It is be	eing filed on or be		of the Issue	Fee;		
		(2)	It is ac	companied by a S	STATEMENT	Γ as set forth	in 37 C.F.R	. §1.97(e);	
		(3)	It is ac	companied by the		forth in 37 (C.F.R. §1.17	(p).	
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Form PTO-1449 (Substitute)

O.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

Attorney Docket Number
LAZE-01011US1

Serial/Patent Number 10/684,883

Information Disclosure Statement
BY APPLICANT
(Use several sheets if necessary)

Applicant/Patent Owner
Thomas F. Rust

Filing/Issue Date 10/14/2003

Group Art Unit 2655

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	nitial if citation considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in not considered. Include copy of this form with next communication to applicant.
	omitted because it was submitted in prior application SN _/, filed, 20, relied on under 35 USC §120. omitted because it was submitted in prior application SN _/, filed, 20, relied on under 35 USC §120.